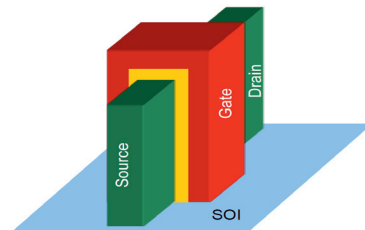


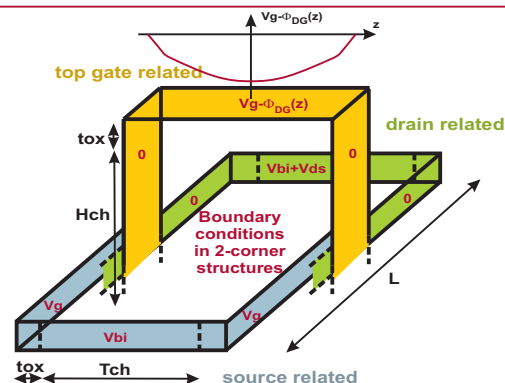
Compact DC Model for Lightly-Doped Short Channel Triple-Gate MOSFETs

- The model is based on an analytical solution of 3D Poisson's equation by the conformal mapping technique.
- 3D Laplace equation is solved in subthreshold regime and thereof the profile of the potential barrier in the channel is calculated.
- For triple-gate devices the influence of the top gate is included.
- BOX influence and quantum confinement are neglected.



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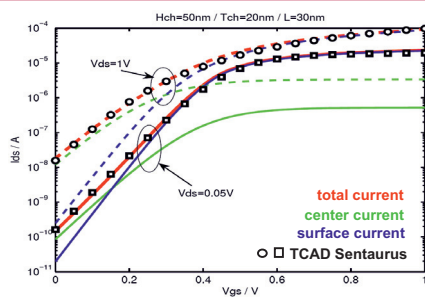
3D Analytical Model for the Electrostatics

- The device structure is decomposed into three 2-corner structures with individual boundary conditions: source related - drain related - top gate related

- From superposition of these three solutions the channel potential at the barrier has been solved in analytical closed form.
- By radical simplification of the solutions published in [1] analytical compact model equations have been derived.

Current Calculation

- The channel current below threshold is derived from the profile of the potential barrier.
- Above threshold a surface channel current is assumed, using a threshold voltage based description derived from the 3D potential solution.
- A simple field-dependent mobility model and a model for the saturation voltage is introduced.
- The shift of the most-leaky path in the channel cross section of a short channel device from the bottom center (subthreshold) to the surface (above threshold) is taken into account by superposing the center current with the surface current in a charge-based current equation [2,3].



$$I_d = \mu W \left[\frac{2V_{th}}{L - X_{min}} (Q_{id,sth} - Q_{is,sth}) - \frac{(Q_{id,sth}^2 - Q_{is,sth}^2)}{4LC'_{ox}} \right]$$

Model Compared to Measurements

- Due to a close link to device structure the model requires a minimum number of fitting parameters while keeping physical insight.
- The model is in good agreement with TCAD down to L=22nm (with reasonable Tch=10nm).
- Comparisons with measurements confirm a high accuracy down to a fin thickness of 30nm and effective channel length of 60nm.

Model Parameters

Device:	L _{drawn} =250nm	L _{drawn} =80nm		
Structural	L	230	53	[nm] effect. channel length
	T _{ch}	30	30	[nm] channel thickness
	H _{ch}	60	60	[nm] channel height
	t _{ox}	2	2	[nm] oxide thickness (SiO ₂)
Mobility	μ ₀	260	180	[cm ² /Vs] low-field mobility
	θ	0.72	1.35	[1] fitting E _{sat} =μ
	V _{sat}	1.45·10 ⁷	1.2·10 ⁷	[cm/s] saturation velocity
	E _{cr}	10 ⁷	10 ⁷	[V/cm] pinch-off electric field
Misc.	N _b	10 ¹⁵	10 ¹⁵	[cm ⁻³] substrate doping
	V _b	-0.327	-0.327	[V] flat-band voltage
	V _{bi}	0.85	0.85	[V] built-in voltage s/d
	φ _i	0.6954	0.6954	[V] inversion potential V _a

Funding

German Federal Ministry of Education and Research, No. 1779X09

German Research Foundation (DFG), Grant KL 1042/3-1

European Commission, FP7 Projects ICT-216171 ("NANOSIL") and IAPP-218255 ("COMON")

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